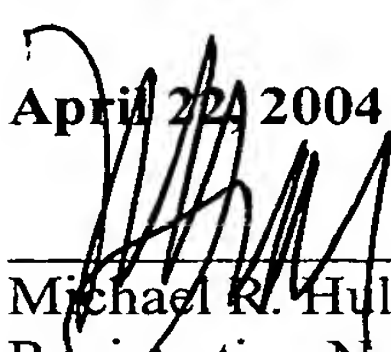




PATENT  
29936/39461

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Application of: Seung Woo Shin and Cha Deok Dong	)	I hereby certify that this paper is being deposited with the United
	)	States Postal Service as first class
Serial No.: 10/631,362	)	mail, postage prepaid, in an
	)	envelope addressed to
Filed: July 31, 2003	)	Commissioner for Patents, P.O.
	)	Box 1450, Alexandria, Virginia
For: Method of Forming Oxynitride Film	)	22313-1450 on this date:
	)	<b>April 22, 2004</b>
Group Art Unit: 2812	)	
	)	Michael R. Hull
Examiner: Alexander G. Ghyka	)	Registration No. 35,902
	)	Attorney for Applicants

**COMMENT ON STATEMENT OF REASONS FOR ALLOWANCE**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, Virginia 22313-1450

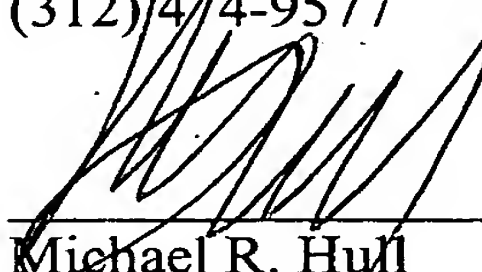
Sir:

In addition to the reasons for allowance set forth in the allowance papers that were mailed in connection with the present application, it is respectfully submitted that the claims are allowable for the additional reasons that the invention defined by the language of the claims is neither anticipated by, nor would have been obvious when taken as a whole in view of, the art of record.

Respectfully submitted,

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**April 22, 2004**